Amendments to the Claims

1. *(Currently Amended)* An electronic device with a micro-electromechanical switch, comprising:

- a piezoelectric element ~~(10)~~ with a piezoelectric layer ~~(12)~~ located between a first and a second electrode layer ~~(11, 13),~~ with at least one electrode ~~(52, 42)~~ being located in each of said electrode layers ~~(11, 13);~~
- a first and a second MEMS electrode ~~(42, 21),~~ said first MEMS electrode ~~(42)~~ being located on a surface of the piezoelectric element ~~(10)~~ and said second MEMS electrode ~~(21)~~ being located on the surface of a substrate ~~(20),~~ so that the first MEMS electrode ~~(42)~~ moves away from and/or towards the second MEMS electrode ~~(21)~~ under the application of an actuating voltage to the piezoelectric element ~~(10),~~

characterized in that at least one of the electrode layers ~~(11, 13)~~ is structured into electrodes ~~(41-43; 51-53)~~ while defining a displacement area in the piezoelectric element ~~(10),~~ in which displacement area the first MEMS electrode ~~(42)~~ is located and which displacement area is, under the application of at least one actuating voltage to the electrodes ~~(41-43; 51-53),~~ capable of strong displacement away from and/or towards the substrate ~~(20)~~ in relation to the rest of the piezoelectric element ~~(10).~~

2. *(Currently Amended)* A device as claimed in claim 1, characterized in that the piezoelectric layer ~~(12)~~ has been polarized during manufacture in a polarization mode, and in that the electrodes have been so defined that an actuating voltage causing a local contraction of the piezoelectric layer ~~(12)~~ can be applied locally.

3. *(Currently Amended)* A device as claimed in ~~claim 1 or 2~~claim 1, characterized in that the piezoelectric layer ~~(12)~~ curves to the left on one side of the displacement area and to the right on an opposite side.

4. *(Currently Amended)* A device as claimed in claim 1, characterized in that the piezoelectric element ~~(10)~~ is clamped to mechanical supports on a first and an opposite second side ~~(30, 31).~~

5. *(Original)* A device as claimed in claim 4, characterized in that the electrodes are defined symmetrically around the displacement area.

6. *(Original)* A device as claimed in claim 1, characterized in that each of the first and the second electrode layers contains at least two electrodes.

7. *(Currently Amended)* An electronic device as claimed in claim 1, characterized in that the second electrode layer ~~(13)~~ is a continuous metal layer while the first electrode layer ~~(11)~~ contains at least three electrodes ~~(41, 42, 43),~~ of which the middle electrode ~~(42)~~ is essentially located opposite the second MEMS electrode ~~(21).~~

8. *(Currently Amended)* An electronic device as claimed in claim 7, characterized in that the first electrode layer ~~(11)~~ is located on the surface facing the second MEMS electrode ~~(21).~~

9. *(Currently Amended)* A method for the preparation of an electronic device as claimed in claim 1, wherein the piezoelectric element ~~(10)~~ is set to a polarization mode by the application of actuating voltages to the electrodes, wherein the piezoelectric layer ~~(12)~~ is so polarized that the piezoelectric layer ~~(12)~~ locally expands and contracts when suitable actuating voltages are applied in the operating mode.

10. *(Currently Amended)* An application of an electronic device as claimed in claim 1, wherein the actuating voltages are so applied to the electrodes that the piezoelectric layer ~~(12)~~ locally expands and contracts.

11. *(Original)* An application as claimed in claim 10, wherein the actuating voltage effecting a local contraction of the piezoelectric layer is lower than the actuating voltage in the direction of the polarization which has already been introduced.